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CONFIRMATION NO. 4946

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SERIAL NUMBER 10/660,151	FILING DATE 09/11/2003 C		:LASS 438	GROUP ART UNIT 2812		ATTORNEY DOCKET NO. 004994 ALRT/ETCH/SILICON	
APPLICANTS							
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Thorsten B. Lill, Santa Clara, CA; Yeajer Arthur Chen, Fremont, CA;Mohit Jain, San Jose, CA; Nicolas Gani, Milpitas, CA; Shing-Li Sung, Hsin-Chu, TAIWAN; Jitske K. Kretz, San Jose, CA; Meihua Shen, Fremont, CA; Farid Abooameri, Pleasanton, CA; *** CONTINUING DATA ******** This appln claims benefit of 60/444,340 01/31/2003 GL *** FOREIGN APPLICATIONS ******* WONG, GL IF REQUIRED, FOREIGN FILING LICENSE GRANTED							
** 12/05/2003 Foreign Priority claimed		7					
35 USC 119 (a-d) conditions	yes Tho Med and	er //	STATE OR	SHEETS	TOT	ΓAL	INDEPENDEN
Verified and Acknowledged Eta	() V X X X X X X X X X X X X X X X X X X	tials	COUNTRY CA	DRAWING 7	CLA 2		CLAIMS 2
ADDRESS 44182 MOSER, PATTERSON APPLIED MATERIALS 595 SHREWSBURY A SUITE 100 SHREWSBURY, NJ 07702	SINC		·				
TITLE Process for etching not	heiliaan aataa with	.d masts s	alootivity sit	ool dimensis = -		اء امسم	
Process for etching polysilicon gates with good mask selectivity, critical dimension control, and cleanliness							